



NV-2400 Surface Profiling System

Accurate Non-Contact Surface Topography

Superior non-destructive 3D Surface Profiling and Analysis

Easy-to-Use Platform Delivers Rapid and Efficient Process Monitoring

Comprehensive and Intuitive software Provides Sample and Application Flexibility

Specification

Measuring method	White-Light Scanning Interferometry(WSI), Phase Shift Interferometry(PSI)
F.O.V Lens	1.0x (Default)
Scanning Range	MAX 270um (PZT Scanning)
Scanning Velocity	12um/sec (1x~5x user-selectable)
Vertical Resolution	WSI : < 0.5nm / PSI : < 0.1nm
Lateral Resolution	0.2 ~ 4um (Objective Lens Dependent)
Illumination	White-light LED Illumination
Tip / Tilt	Probe Tip/Tilt $\pm 6^\circ$ Manual
Interferometric Objectives	5Lens Available (Manual Turret)
Step Height Repeatability	0.1% @1 σ (Standard Sample 8um)
X,Y Stroke	100x100mm (Motorized)
Z Stroke	100mm (Manual)
Stage Size	230x230mm

Option

F.O.V Lens	0.55x, 0.75x, 1.0x, 1.5x, 2.0x (Selectable)
Interferometry Objectives	2.5x, 5x, 10x, 20x, 50x, 100x (Selectable)
Scanning Range	Max 10mm available
Vaccum Stage	Option



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